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In re Application of
Selvamanickam, Venkat et al.

Serial Number: 10/602,468

Filed: June 23, 2003

For: METALORGANIC CHEMICAL VAPOR
DEPOSITION (MOCVD) PROCESS AND
APPARATUS TO PRODUCE MULTI-LAYER
HIGH-TEMPERATURE SUPERCONDUCTING
(HTS) COATED TAPE

PETITION UNDER
M.P.E.P. 708.02 IX

This is in response to the petition filed February 12, 2004, requesting that the above-identified application be granted Special Status under Section 708.02 IX of the MPEP and 37 CFR 1.102 (b) (**no fee required**).

The request for Special Status considered under Section 708.02 IX of the MPEP is granted because the criteria under 37 CFR 1.102(b) has been met.

Accordingly the petition is **GRANTED**.

Marian C. Knode

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